



An Undergrad Course of Southeast University

Lecture 13

Final Review

Course ID: B3060221

Instructor: Prof. Liyi Li (李力一)

School of Electronic Science and Engineering,
Southeast University

Format

- Total 40 pts;
- Fill-the-blanks: 10 questions, 2 pts each, 20 pts total.
- Short answers: 4 questions, 5 pts each, 20 pts total.

Example Questions

- Question: What is the full name of MEMS?

Answer: micro-electromechanical system

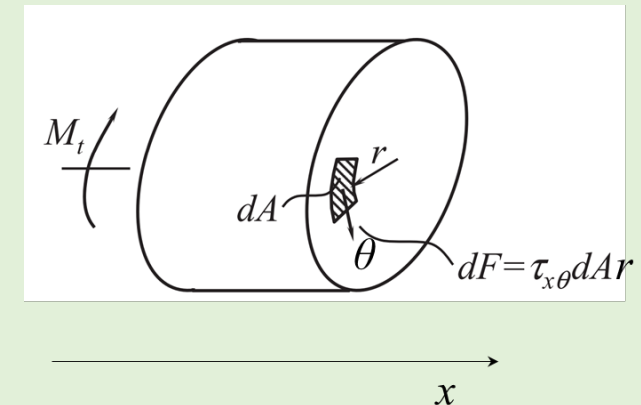
- Question: List a process for adding a layer of film in vacuum? _____

Answer: sputter, evaporation (either one is correct)

- Question: Calculate the polar moment of inertia of the circular cross section on the right, where the radius is r_0 .

Answer:

$$J = \int r^2 dA = \int_0^{2\pi} \int_0^{r_0} r^2 \cdot r dr d\theta = \int_0^{2\pi} \int_0^{r_0} r^3 dr d\theta = \frac{\pi r_0^4}{2}$$



Concept

Dimensional Analysis

Equations

Express dimensions of physical quantities using FLT units (PPT, P37)

Concept

| | | | |
|---|--------------------------|------------------------------------|--------------------|
| Crystalline orientation, graphic representation | Anisotropy | Single and poly crystal | Photolithography |
| Steps of photolithography | Positive/negative resist | Additive and subtractive processes | Etch anisotropy |
| Mean free path | Sputter vs. plasma etch | Anisotropic wet etch | Isotropic wet etch |

Equations

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|------------------------|----------------------|-----------------------------|
| Spin-coating thickness | Photoresist contrast | Photolithography resolution |
|------------------------|----------------------|-----------------------------|

L03

Concept

| | | | |
|----------------------|-------------------|-----------------------|-------|
| Evaporation | Shadowing effect | Sputter Deposition | CVD |
| Si oxidation methods | CVD reaction rate | Deposition uniformity | LPCVD |
| PECVD | ALD | Step coverage | |

Equations

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|---------------|--|--|
| Arrhenius Law | | |
|---------------|--|--|

L04

Concept

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|---------------------|-------------------|--------------|--------------|
| Moment | Free body diagram | Normal force | Shear force |
| Tensile force | Compressive force | Yield | Neutral line |
| Radius of curvature | | | |

Equations

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|--------------------------------|-------------------------------------|-----------------------------|
| Force equilibrium | Stress | Strain |
| Moment of inertia | Moment-curvature relationship | Neutral surface location |
| Euler-Bernoulli equation (P47) | Deflection of Cantilever beam (P52) | Castigliano's theorem (P62) |
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| Concept | | | |
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| Equations | | |
|---|-----------------------------------|--|
| Effective stiffness of springs with parallel and series connections | Stiffness of a straight beam (P8) | |
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| Concept | | | |
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| Equations | | |
|---|---|---|
| Coriolis acceleration (P12) | Centrifugal force (P15) | Free vibration of undamped system (P21) |
| Free vibration of undamped system (P25) | Forced vibration of undamped system (P26) | Quality factor (P29) |
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| Concept | | | |
|---------------|-----------------|--|--|
| Piezoelectric | Piezoresistance | | |
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| Equations | | |
|---------------------|--|---|
| Capacitance | Inductance | Kirchhoff's laws |
| Coulomb's law | Electrostatic force on vertically moving parallel plates (P16) | Electrostatic force on laterally moving parallel plates (P17, 18) |
| Lorentz force (P23) | | |
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Concept

Effective flexural rigidity
(P5)

Equations

Neutral line position of composite
beam(P7)

Concept

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Equations

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| Deflection of a strip under uniform pressure (P5) | Governing Equation for accelerometer (P10) | |
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L10

| Concept | | | |
|------------------|----------------|-----------|----------------|
| Conduction | Convection | Radiation | Thermoresistor |
| Seebeck's Effect | Peltier Effect | | |
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| Equations | | |
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| Temperature distribution across uniformly heated beam (P6) | | |
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| Concept | | | |
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| Compressibility | | | |
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| Equations | | |
|--|------------------|---|
| Shear stress between moving plate and viscous fluid (P6) | Fick's first law | Velocity distribution of flow in a pipe (P19) |
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| Concept | | | |
|---------------------|--------------------|-----------|------------|
| Transverse wave | Phase | frequency | wavenumber |
| Specular reflection | Diffuse reflection | | |
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| Equations | | |
|-------------------|-------------------|--|
| Law of reflection | Law of refraction | |
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